

862.C2238

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE



Inventor Application of:

Shigeyuki UZAWA

Application No.: 09/865,454

Filed: May 29, 2001

For: EXPOSURE APPARATUS, DEVICE
MANUFACTURING METHOD,
SEMICONDUCTOR
MANUFACTURING PLANT AND
METHOD OF MAINTAINING
EXPOSURE APPARATUS

Examiner: Unassigned

Group Art Unit: 2881

August 27, 2001

Commissioner for Patents
Washington, D.C. 20231

CLAIM TO PRIORITY

Sir:

Applicant hereby claims priority under the International Convention and all rights to which he is entitled under 35 U.S.C. § 119 based upon the following Japanese Priority Application:

JAPAN

2000-163845

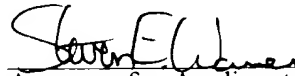
May 31, 2000

A certified copy of the priority document is enclosed.

10 2881 UNIT ROOM

Applicant's undersigned attorney may be reached in our Washington, D.C. office by telephone at (202) 530-1010. All correspondence should continue to be directed to our address given below.

Respectfully submitted,



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JAPAN PATENT OFFICE

Shigeyuki Uzawa

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